



Japan TC Chapter Meeting of Liquid Chemical Global Technical Committee

Meeting Summary and Minutes

Thursday, August 20, 2020 14:00 -17:00

SEMI Japan, Tokyo, Japan

TC Chapter Announcements

Next TC Chapter Meeting

Friday January 29, 2021 13:00-15:00

SEMI Japan Office, Tokyo Japan

Table 1 Meeting Attendees

Italics indicate virtual participants

Co-Chairs: Hiroyuki Araki (SCREEN Semiconductor Solutions)

SEMI Staff: Hirofumi Kanno

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
ADVANCE ELECTRIC	Sasao	Kimihito	SCREEN Semiconductor Solutions	Araki	Hiroyuki
Nihon Entegris	Nagafuchi	Takuya	Rion	Kondo	Kaoru
<i>Nihon Pall</i>	<i>Takakura</i>	<i>Tomoyuki</i>			
<i>Organo</i>	<i>Futatsuki</i>	<i>Takashi</i>			
<i>SCREEN Semiconductor Solutions</i>	<i>Fujitani</i>	<i>Yoshiyuki</i>	SEMI Japan	Hirofumi	Kanno

Table 2 Leadership Changes

None

Table 3 Committee Structure Changes

None

Table 4 Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
6575	Line Item Revision to SEMI F61-0617, Guide to Design and Operation of a Semiconductor Ultrapure Water System	
Line Item 1	SEMI F61 - Update Sections 10 and 17 and Appendices 1 and 7 to align with 2019 IRDS	Failed
6576	Line Item Revision to SEMI F63-0918, Guide for Ultrapure Water Used in Semiconductor Processing	
Line Item 1	SEMI F63 - Provide clarification to limitations and Table 2	Failed
Line Item 2	SEMI F63 - Update Table 1, including corresponding footnotes and text, to align with 2019 IRDS while also providing achievable limits with available metrology	Failed
6577	Line Item Revision to SEMI F75-0617, Guide for Quality Monitoring of Ultrapure Water Used in Semiconductor Manufacturing	
Line Item 1	SEMI F75 - Update Sections 5 and 8 to align with 2019 IRDS, while also providing achievable limits with available metrology	Failed

Table 4 Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
6606	Reapproval to SEMI C69-1015, Test Method for the Determination of Surface Areas of Polymer Pellets	Passed
6489	New Standard: Guide for Reporting Chemical Mechanical Planarization (CMP) Polishing Pad Hardness used in Semiconductor Manufacturing	Passed with editorial change
6645	Revision to SEMI F40-0699E (Reapproved 0918), Practice for Preparing Liquid Chemical Distribution Components for Chemical Testing, with title change to: Practice for Preparing Liquid Chemical Distribution Components and Neat Polymers or Chemical Testing	Failed

#1 **Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

#2 **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 5 Activities Approved by the GCS between meetings of the TC Chapter

None

Table 6 Authorized Activities

None

Table 7 Authorized Ballots

None

Table 8 SNARF(s) Granted a One-Year Extension

None

Table 9 SNARF(s) Abolished

None

Table 10 Standard(s) to receive Inactive Status

None

Table 11 New Action Items

None

Table 12 Previous Meeting Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
2019415_01	SEMI Staff	To provide a list of participating companies for CMP PSD Working Group Closed

1 Welcome, Reminders, and Introductions

Mr. Araki called the meeting to order at 14:00. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

Attachment: 01-02_SEMI Standards Required Elements_June2020_E+J,



2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

Motion: To approve the previous meeting minutes of Liquid Chemical Japan TC Chapter on December 11, 2020 with an editorial change.

By / 2nd: Nagafuchi Takuya (Nihon Entegris)/ Kaoru Kondo (Rion)

Discussion: Members would like to have had the list to be sent within 1 months of the last meeting.

Vote: 3 in favor and 0 opposed. **Motion passed**

Attachment: 02-00_LC Minutes_Draft_20191211_R0.1

3 Liaison Reports

3.1 *Liquid Chemical Europe TC Chapter*

-- Hirofumi Kanno (SEMI Japan) reported for the *Liquid Chemical Europe* TC Chapter. Of note:

No report since no meeting was held.

3.2 *Liquid Chemical North America TC Chapter*

-- Hirofumi Kanno (SEMI Japan) reported for the *Liquid Chemical North America* Europe TC Chapter. Of note:

Attachment: 03_01_NA Liquid Chemicals Liaison Report April 2020-v1,

3.3 *SEMI Staff Report*

-- Hirofumi Kanno (SEMI Japan) gave the SEMI Staff Report. Of note:

Attachment: 03_02_SEMI Staff Report 2020_0525_V0.2

4 Ballot Review

NOTE 1: TC Chapter adjudication on ballots reviewed is detailed in the Audits & Review (A&R) Subcommittee Forms for procedural review. The A&R forms are available as attachments to these minutes. The attachment number for each balloted document is provided under each ballot review section below.

4.1 Document # 6575, Line Item Revision to SEMI F61-0617, Guide to Design and Operation of a Semiconductor Ultrapure Water System

4.1.1 Line Item 1: SEMI F61 - Update Sections 10 and 17 and Appendices 1 and 7 to align with 2019 IRDS

Attachment: 04-01_6575_Ballot Line-Item report template_r2,

4.2 Document # 6576, Line Item Revision to SEMI F63-0918, Guide for Ultrapure Water Used in Semiconductor Processing

4.2.1 Line Item 1: SEMI F63 - Provide clarification to limitations and Table 2

4.2.2 Line Item 2: SEMI F63 - Update Table 1, including corresponding footnotes and text, to align with 2019 IRDS while also providing achievable limits with available metrology

Attachment: 04-02_6576_Ballot Line-Item report template_r2,

4.3 Document # 6577, Line Item Revision to SEMI F75-0617, Guide for Quality Monitoring of Ultrapure Water Used in Semiconductor Manufacturing



4.3.1 Line Item 1: SEMI F75 - Update Sections 5 and 8 to align with 2019 IRDS, while also providing achievable limits with available metrology

Attachment: 04-03_6576_Ballot Line-Item report template_r2,

4.4 Document # 6606, Reapproval to SEMI C69-1015, Test Method for the Determination of Surface Areas of Polymer Pellets

Attachment: 04-04_6606_Ballot Report Template_r2

4.5 Document # 6489, New Standard: Guide for Reporting Chemical Mechanical Planarization (CMP) Polishing Pad Hardness used in Semiconductor Manufacturing

Attachment: 04-05_6489_Ballot Report Template_r2

4.6 Document #6645, Revision to SEMI F40-0699E (Reapproved 0918), Practice for Preparing Liquid Chemical Distribution Components for Chemical Testing, with title change to: Practice for Preparing Liquid Chemical Distribution Components and Neat Polymers or Chemical Testing

Attachment: 04-06_6645_Ballot Report Template_r2

5 Subcommittee and Task Force Reports

No Reports

6 Old Business

6.1 *Confirmation of previous action item*

-- Done 20190415_01 To provide a list of participating companies for CMP PSD Working Group

7 New Business

8 Next Meeting and Adjournment

The next meeting is scheduled for Friday January 29, 2021 13:00-15:00 at SEMI Japan Office, Tokyo Japan. See <http://www.semi.org/standards-events> for the current list of events.

Adjournment: [17:00]>.

Respectfully submitted by:

Hirofumi Kanno

Manager

SEMI Japan

Phone: +81.3.3222.5760

Email: hkanno@semi.org

Minutes tentatively approved by:

Hiroshi Tomita (KIOXIA), Co-chair	<Date approved>
Hiroyuki Araki (SCREEN Semiconductor Solutions), Co-chair	<Date approved>



Table 13 Index of Available Attachments#1

<i>Title</i>	<i>Title</i>
01-02_SEMI Standards Required Elements_June2020_E+J	04-02_6576_Ballot Line-Item report template_r2
02-00_LC Minutes_Draft_20191211_R0.1	04-03_6576_Ballot Line-Item report template_r2
03_01_NA Liquid Chemicals Liaison Report April 2020-v1,	04-04_6606_Ballot Report Template_r2
03_02_SEMI Staff Report 2020_0525_V0.2	04-05_6489_Ballot Report Template_r2
04-01_6575_Ballot Line-Item report template_r2	04-06_6645_Ballot Report Template_r2
04-02_6576_Ballot Line-Item report template_r2	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.